



<b>Session Title:</b>	<b>[TuE1] Plasma Surface Interaction</b>
<b>Session Date:</b>	<b>November 12 (Tue.), 2024</b>
<b>Session Time:</b>	<b>13:00-14:25</b>
<b>Session Room:</b>	<b>Room E (Sicily Room, 1F, Paradise Hotel Busan)</b>
<b>Session Chair:</b>	<b>Prof. Chin-Wook Chung (Hanyang Univ., Korea)</b>

**[TuE1-1] [Plenary]**

**13:00-13:45**

**Atom Recombination on Surfaces in Plasmas - an Experimental Study**

Jean-Paul Booth (Inst. Polytechnique de Paris, France)

**[TuE1-2]**

**13:45-14:05**

**Plasma Etching of Silicon Carbide Using Low-GWP Heptafluoroisopropyl Methyl Ether**

Sanghyun You and Chang-Koo Kim (Ajou Univ., Korea)

**[TuE1-3]**

**14:05-14:25**

**Plasma-Enhanced Atomic Layer Etching of Tantalum Nitride with Surface Fluorination and Ar Sputtering**

Hojin Kang, Sangbae Lee, Minsung Jeon, and Heeyeop Chae (Sungkyunkwan Univ., Korea)